



Sheet 1 of 2

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				ATTY. DOCKET NO. LBP-PT033		SERIAL NO. 10/766,463	
				APPLICANT Rembe et al.			
				FILING DATE January 28, 2004		GROUP 2877	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>lpe</i>	AA	6,084,672	07/04/00	Andrew Lewin	<i>/</i>	<i>/</i>	
<i>lpe</i>	AB	6,404,545	06/11/02	Hiroshi Ishiwata	<i>/</i>	<i>/</i>	
<i>lpe</i>	AC	6,181,431	01/30/01	Bernard Siu	<i>/</i>	<i>/</i>	
<i>lpe</i>	AD	US 2002/089740	07/11/02	Jeffrey A. Beckstead Wetzel et al.	<i>/</i>	<i>/</i>	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
<i>lpe</i>	AE	JP 61-013233	01/86	Japan - Abstract	<i>/</i>	<i>/</i>	
<i>lpe</i>	AF	WO 00/33727	06/00	PCT	<i>/</i>	<i>/</i>	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
<i>lpe</i>	AG	Q. S. Davis et al., "Using a Light Microscope to Measure Motions with Nanometer Accuracy", Optical Engineering, Vol. 37, 1998, pp. 1299-1304					
<i>lpe</i>	AH	N. F. Smith et al., "Non-Destructive Resonant Frequency Measurements on MEMS Actuators", Proc. of IEEE 01CH37167, 39 th Annual Internat'l Reliability Physics Symposium, Orlando, FL 2001, pp. 99-105					
<i>lpe</i>	AI	Microscope Scanning Vibrometer MSV 300, Polytec Hardware Manual for Scanner Controller MSV-Z-040, Microscope Adapter OFV-074 and Scanner Unit OFV-073, Polytec GmbH, Waldbronn, Germany 2002					

EXAMINER <i>Paul J. Chudles</i>	DATE CONSIDERED <i>9/22/05</i>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.